

501.41175X00/340101349US1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED
CENTRAL FAX CENTER

APR 18 2005

Applicant: Hiroyuki NAKANO et al.
 Serial No.: 10/075,244
 Filed: 15 February 2002
 For: METHOD AND APPARATUS FOR PLASMA PROCESSING
 Group: 1762
 Examiner: M. Padgett
 Conf. No.: 7857

*Entered per
RCE filed
6/20/05
JL*

AMENDMENT AFTER FINAL AMENDMENT

Mail Stop AF
EXPEDITED PROCESSING REQUESTED UNDER 37 CFR §1.116
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, Virginia 22313-1450

18 April 2005

Sir:

In response to the final Office Action mailed 18 November 2004 in connection with the above-identified application, the following amendments and remarks are respectfully submitted.

In accordance with 37 CFR §1.121 in the Final Rule effective 30 July 2003, and as revised in the Final Rule effective 21 October 2004, each section of amendment begins on a new page, and changes are shown by strike-through (or double brackets where appropriate) and underlining to indicate deletions and additions, respectively. A complete listing of all claims ever presented in the application is given with the current status of each claim, and only the text of all pending and withdrawn claims is presented in full, with those pending/withdrawn claims not being amended herein being presented in clean version.